EAST - [Untitled1:1]

File View Edit Tools Window Help

- Drafts
- Pending
- Active
  - L1: (2) (("6676822") or ("6482307")).PN.
  - L2: (388035) pad
  - L3: (2) l1 and l2
  - L4: (53555) ("451").CLAS.
  - L5: (8928) polishing adj pad
  - L6: (190896) alumina
  - L7: (56675) silicon adj carbide
  - L8: (1138) l5 same (l6 or l7)
  - L9: (217493) wafer
  - L10: (1022) l8 and l9
  - L11: (87) l5 near4 (l6 or l7)
  - L12: (72) l11 and l9
  - L13: (1) ("20040195106").PN.
  - L14: (310506) ceramic
  - L15: (1) l13 and l14
  - L16: (0) l13 and l5
  - L17: (0) l13 and l2
  - L18: (2) l1 and l5
- Failed
- Saved
- Favorites
- Tagged (0)
- UDC
- Queue
- Trash

Search | List | Browse | Queue | Clear

DBs: US-PGPUB; USPAT

Plurals

Default operator: ADJ

Highlight all hit terms initially

l1 and l5

BRS form | IS&R form | Image | Text | HTML

	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Inventor	U	S	C	P	1					PT	
1	US 6676822 B1	20040113	10	Method for electro chemical mechanical deposition	205/93	205/101; 205/117;	Talieh; Homayoun	☐	☑	☐	☐	☐	☐	☐	☐	☐	☐	
2	US 6482307 B2	20021119	16	Method of and apparatus for making electrical contact to wafer surface for	205/103	205/137; 205/149;	Ashjaee; Jalal et al.	☐	☑	☐	☐	☐	☐	☐	☐	☐	☐	

Hits | Details | HTML

Ready

NUM